



IFW

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Takeshi KIJIMA et al.

Application No.: 10/724,635

Filed: December 2, 2003

Docket No.: 117926

For: METHOD OF MANUFACTURING OXIDE THIN FILM, METHOD OF
MANUFACTURING FERROELECTRIC THIN FILM, FERROELECTRIC THIN
FILM, FERROELECTRIC MEMORY DEVICE, AND FERROELECTRIC
PIEZOELECTRIC DEVICE

PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Please consider the following:

Amendments to the Specification; and

Remarks.